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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Applicant:

Matthew Prince et al.

Serial No.: 10/762,849

Filed: January 22, 2204

For: Reducing Wafer Defects from
Chemical Mechanical Polishing

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Art Unit: 3723

Examiner: Hadi Shakeri

Docket: ITL.0941US
P15694

Assignee: Intel Corporation

Mail Stop **Amendment**
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REPLY TO PAPER NO. 081105

Sir:

In response to the office action mailed August 15, 2005, please amend the above-referenced patent application as follows:

Date of Deposit: November 10, 2005

I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as **first class mail** with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Cynthia L. Hayden
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